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(54) Title (EN): ULTRA-HIGH VACUUM TRANSPORT AND STORAGE

(54) Title (FR): TRANSPORT ET STOCKAGE SOUS ULTRAVIDE

(57) Abstract:

(EN): An apparatus for transporting or storing at least one semiconductor wafer in an ultra-high vacuum is provided. A portable vacuum transfer pod is provided comprising an internal wafer storage chamber for storing one or more wafers and a wafer support for supporting at least one wafer within the internal wafer storage chamber. A passively capable vacuum pump capable of passive vacuum pumping is in fluid connection with the internal wafer storage chamber and is mechanically connected to the portable vacuum transfer pod. A shut off valve for opening and closing the fluid connection is between the passively capable vacuum pump and the internal wafer storage chamber.

(FR): L'invention concerne un appareil de transport ou de stockage d'au moins une tranche de semi-conducteur sous ultravide. Une capsule de transfert sous vide transportable comprend une chambre interne de stockage de tranches permettant de stocker une ou plusieurs tranches et un support de tranches destiné à supporter au moins une tranche à l'intérieur de la chambre interne de stockage de tranches. Une pompe à vide à capacité passive permettant un pompage passif de vide est en communication fluïdique avec la chambre interne de stockage de tranches et est reliée mécaniquement à la capsule de transfert sous vide transportable. Une vanne d'isolement permettant d'ouvrir et de fermer la connexion fluïdique est située entre la pompe à vide à capacité passive et la chambre interne de stockage de tranches.

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